



**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

Applicant(s): Tom Tse, et al.

Title: METHOD AND SYSTEM FOR DOSE CONTROL DURING AN ION  
IMPLANTATION PROCESS

App. No.: 10/082,567 Filed: February 25, 2002

Examiner: Mary A. El Shammaa Group Art Unit: 2881

Atty. Dkt. No.: 1458.TT4763

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Commissioner for Patents  
PO Box 1450  
Alexandria, VA 22313-1450

**AMENDMENT/RESPONSE**

Dear Sir:

In response to the Office Action mailed May 23, 2003 regarding the above captioned patent application, the Applicant(s) hereby respectfully submit the following amendment and response.